

Docket No.: 4590-390

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Liviu NICU et al.

U.S. Patent Application No. n/a

Filed: *herewith*

For: MICROMACHINED GYROSCOPIC SENSOR WITH DETECTION IN THE PLANE
OF THE MACHINED WAFER

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Preliminary to examination of the above-referenced application, please amend the application as follows: